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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Rothschild, et al.  
Serial No: 10/020,047  
Confirmation No: 4420  
Filed: December 7, 2001  
For: ATTENUATING PHASE SHIFT MASK FOR  
PHOTOLITHOGRAPHY

Examiner: Rosasco, Stephen D.  
Art Unit: 1756

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**CERTIFICATE OF MAILING UNDER 37 C.F.R. §1.8(a)**

The undersigned hereby certifies that this document is being placed in the United States mail with first-class postage attached, addressed to Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on the 3<sup>rd</sup> day of November, 2003.

*Denise M. Donahue*  
Denise M. Donahue

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Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**AMENDMENT**

Sir:

In response to the Office Action mailed August 1, 2003, please amend the above-identified application as follows. Changes to the claims are shown by strike through for deleted matter and underlining for added matter.

11/06/2003 CNGUYEN 00000058 10020047

01 FC:2202  
02 FC:2201

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